

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : S. Yamazaki, et al. Art Unit : Unknown
Serial No. : New Divisional Application Examiner : Unknown
Filed : August 26, 2003
Title : SEMICONDUCTOR THIN FILM AND ITS MANUFACTURING METHOD
AND SEMICONDUCTOR DEVICE

Commissioner for Patents
P.O. Box 1450
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INFORMATION DISCLOSURE STATEMENT

Copies of the references listed on the attached form PTO-1449 are enclosed.

Under 35 USC §120, this application relies on the earlier filing date of application serial number 10/077/141, filed on February 15, 2002. The cited references were submitted to and/or cited by the Office in the prior application and, therefore, are not provided in this application.

This statement is being filed with the application. Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 8/26/03



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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 07977-126004	Application No.
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant S. Yamazaki et al.	
		Filing Date	Group Art Unit

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	4,907,053	03/1990	Ohmi			
	AB	5,042,918	08/1991	Suzuki			
	AC	5,274,485	12/1993	Narita et al.			
	AD	5,294,821	03/1994	Iwamatsu			
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	AK	5,639,698	06/17/1997	Yamazaki et al.			
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	AU	6,084,247	07/04/2000	Yamazaki et al.			
	AV	6,107,639	08/22/2000	Yamazaki et al.			

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AW	06-232059	08/19/1994	JAPAN			Yes	
	AX	06-244103	09/02/1994	JAPAN			Abst.	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AY	07-321339	12/08/1995	JAPAN			Abst.	
	BA	08-255916	10/1/1996	JAPAN			Abst.	

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	BB	Takahashi, et al., "Oxide-semiconductor interface roughness and electrical properties of polycrystalline silicon thin-film transistors", Appl. Phys. Lett., Vol. 64, No. 17, pp. 2273-2275, April 25, 1994.
	BC	Cao, et al., "A Low Thermal Budget Polysilicon Thin Film Transistor Using Chemical Mechanical Polishing", Internal Display Research Conference, pp. 294-297, October 1994.
	BD	Shimokawa, et al., "Characterization of High-Efficiency Cast-Si Solar Cell Wafers by MBIC Measurement", Japanese Journal of Applied Physics, Vol. 27, No. 5, pp. 751-758, May 1988.
	BE	Wolf, S., et al. "Silicon Processing for the VLSI Era Volume 1: Process Technology", Lattice Press, Sunset Beach, CA, pp. 61-65, 335.
	BF	Wolf, S., "Silicon Processing for the VLSI Era Volume 3: The Submicron MOSFET", Sunset Beach, CA, p. 648.

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